PATENT TO

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the application of)
••	Examiner: Unassigned
Gotkis et al.	
	Art Unit: 2855
Application No: 10/671,978	
9.4	Docket No: LAM2P438
Filed: September 26, 2003	
	Date: September 1, 2004
For: METHOD AND APPARATUS FOR WAFER)	
MECHANICAL STRESS MONITORING AND)	
WAFER THERMAL STRESS MONITORING)

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450 Alexandria, VA 22313-1450 on September 1, 2004.

Signed Melinda M. Ward

REQUEST TO RESCIND PREVIOUS NONPUBLICATION REQUEST & NOTICE OF FOREIGN FILING

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

A request that the above-identified application not be published under 35 U.S.C. 122(b) (non-publication request) was included with the above-identified application on filing pursuant to 35 U.S.C. 122(b)(2)(B)(i).

I hereby **RESCIND** the previous non-publication request. If a **notice** of foreign or international filing is or will be required by 35 U.S.C. 122(b)(2)(B)(iii) and 37 CFR 1.213(c), I hereby provide such **NOTICE**. This notice is being provided no later than forty-five (45) days after the date of such foreign or international filing.

Respectfully submitted,

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